Performance Comparison between Copper, Carbon Nanotube and Optics for On-chip Interconnects

> Mar. 18. 2007 Hoyeol Cho, Kyung-Hoae Koo, Pawan Kapur, and Krishna C. Saraswat

### Outline

#### Motivation

Modeling of Cu/low-K, CNT, and Optics > RLC Modeling of Cu/low-K and CNT

Optical Interconnect Modeling

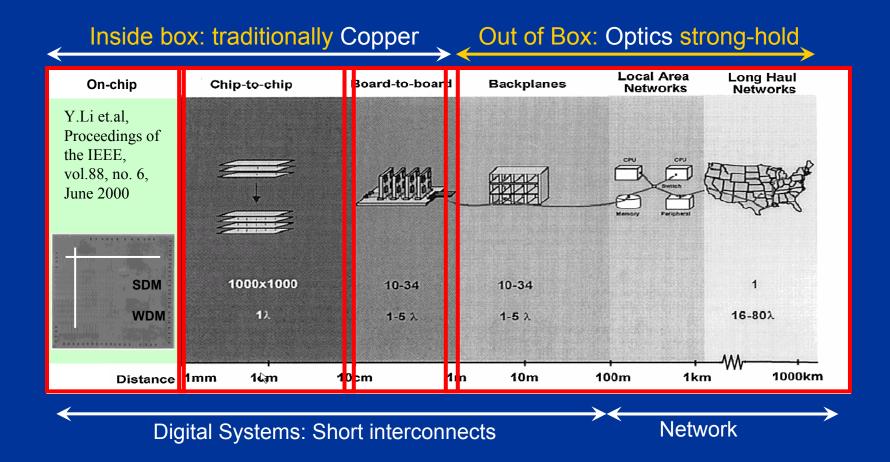
#### Performance Comparison

- Primary metrics
  - ✓ Bandwidth density
  - ✓ Latency
  - ✓ Power
- Compound metrics
  - Bandwidth density/Latency/Power

#### Conclusion



### **Interconnect Hierarchy**

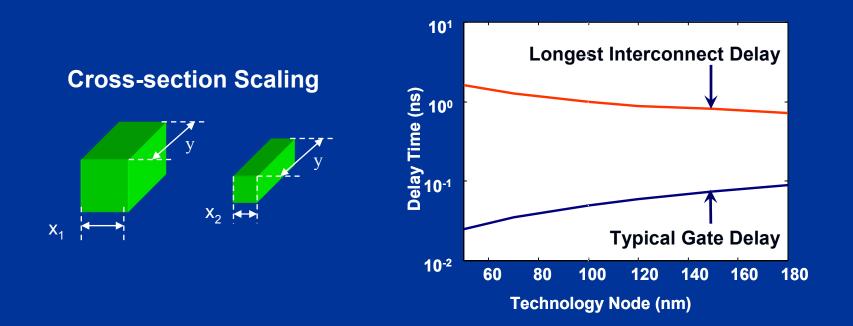


#### Interconnect level of this talk: On-chip global wires



### Limit of On-chip Electrical Interconnect: Latency

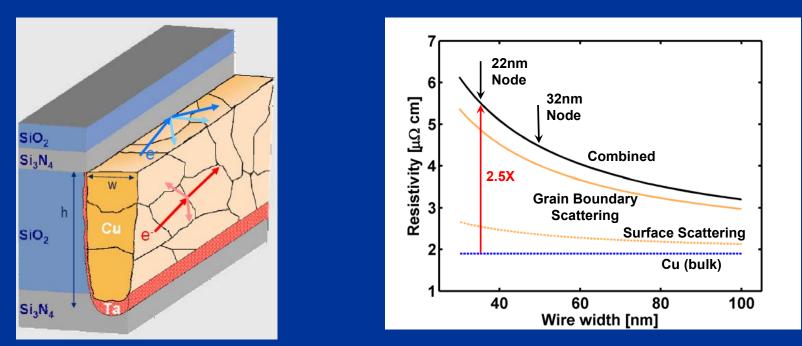
#### On-chip wires are getting slower



### Wire delay is deteriorating wrt gate delay with scaling even with low-k materials



### Limit of On-chip Electrical Interconnect: Resistance



Based on W. Steinhogl et.al. Phys. Rev. B, 2002

Resistivity increases as wire dimensions and grain size become comparable to the bulk mean free path of electrons

- Grain boundary scattering
- Surface scattering



### Limit of On-chip Electrical Interconnect: Repeaters



#### A long global link w/o Repeaters

 $t_{total} = 0.4 R_w C_w l^2$ 

#### Delay (helps enormously)

- Best possible interconnect delay
- Linear with length
- Scales better
- But is it good enough?

## Repeaters have power and area penalty: need new interconnect technologies...



With Repeaters

$$t_{total} = 5l\sqrt{r_o C_{mos} R_w C_w}$$
$$= 2l\sqrt{(0.4R_w C_w)t_{FO4}}$$

### **Alternative Candidates**

	Pros	Cons
Optics	<ul> <li>Low loss for longer wire and higher bandwidth</li> <li>Lower power at higher bandwidth and switching activity</li> <li>Wavelength Division Multiplexing</li> </ul>	<ul> <li>≻ Larger pitch(~0.6µm)</li> <li>→ Lower BW density</li> </ul>
Carbon Nanotube (CNT)	<ul> <li>&gt; Small device: ~nm diameter</li> <li>&gt; Longer mean free path</li> <li>→ Resistance ↓</li> </ul>	> Power

# Imperative to quantify performance metrics of alternative candidates comparing with Cu/low-K



### **Performance Metrics**

Primary Metric	Cu, CNT, Optics	
Bandwidth	Level-off (10~20Gb/s) Design paradigm: Multi-core	
Area	Different pitch $\rightarrow$ BW density	
Latency	Core to core communication	
Power	Budget: hungry at chip level	
Compound Metric	BW density/Latency/Power	

Extensive analysis on performance comparison between Cu, CNT and optics for on-chip levels using primary and compound metrics



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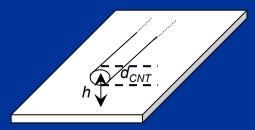
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**RLC Model for Single-wall CNT:** Capacitances  $(C_E, C_Q)$ 

$$C_w = \frac{C_E \cdot C_Q}{C_E + C_Q}$$

 $\Box$  Electrostatic Capacitance ( $C_E$ )



$$f_E = 2\pi\varepsilon / \ln\left(\frac{d_{CNT}}{h}\right)$$

 $0.17 \mu / \mu / \mu / \mu$ 

Quantum Capacitance ( $C_o$ )

$$C_Q = \frac{2e^2}{hv_F} \sim 0.1 fF / \mu m (\sim C_E)$$

[P. J. Burke, Trans. on Nanotechnology, 2002]

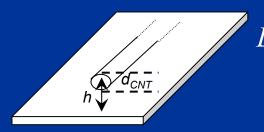
The quantum and electrostatic capacitances are in series, and have the same orders of magnitude



### RLC Model for Single-wall CNT: Inductances $(L_m, L_k)$

$$L_w = L_m + L_k$$

#### $\Box$ Magnetic inductance ( $L_m$ )



$$=\frac{\mu}{2\pi}\ln\left(\frac{d_{CNT}}{h}\right)$$

=1.6nH/mm

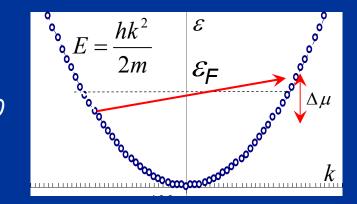
#### $\Box$ Kinetic inductance ( $L_k$ )

$$L_k \equiv \frac{h}{2v_F e^2} \sim 16 \,\mu H \,/\,mm$$

#### [P. J. Burke, Trans. on Nanotechnology, 2002]

#### 4 orders higher magnitude → Inductance effects becomes important

*I≠0* 





#### Mar. 18, 2007 Hoyeol Cho

### RLC Model for Single-wall CNT: Resistance

$$R_{w} = R_{C} + R_{Q} \left( 1 + \frac{l}{l_{o}} \right)$$

#### Contact resistance (R<sub>c</sub>)

► 120K $\Omega \rightarrow \sim K\Omega$  per nanotube [H. Dai, Applied Phys. A, 2004] Quantum resistance (R<sub>o</sub>)

$$R_{Q} = \frac{h}{4e^2} = 6.45K\Omega$$

[P. J. Burke, Trans. on Nanotechnology, 2002]

#### $\Box$ Wire resistance ( $R_w$ )

- linear model [J.Y. Park, Nano Letters, 2004]
- > Good quality CNT:  $l_o = 1.6 \mu m$

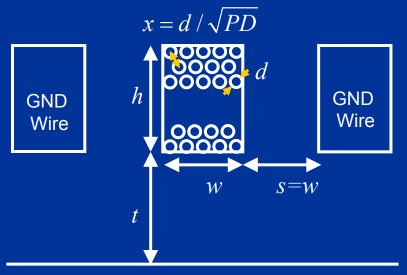
### Resistance is linear dependence with wire length multiplied by Quantum resistance



### **RLC Model for Bundled CNT**

#### **CNT** bundle

- Same wire dimension with Cu
- Packing density



GND plane

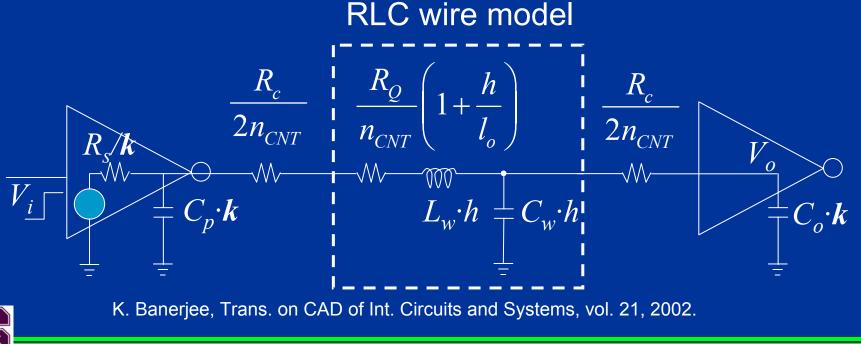
Equiv. RLC for CNT Bundle
$C_{_W} \sim C_{_E}$
$L_{w} \sim L_{k} / 4n + L_{m}$
$R_{c} \sim 0$
$R_{w} = \frac{R_{Q}}{n} (1 + l/l_{o})$



### **Repeater Model: RLC**

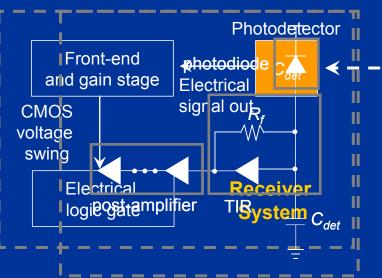
#### RLC model

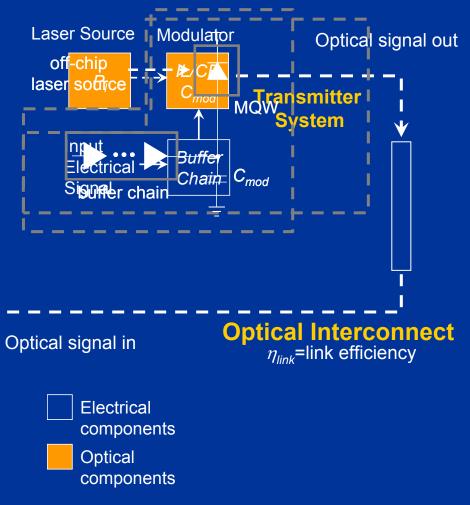
- > No closed form solution: k (driver size) and h (repeater spacing)
- Newton-Raphson numerical iteration method
- Increase in the inductance ratio to resistance
  - $\checkmark k \downarrow$  and  $h \uparrow$
  - the total repeater capacitance reduces resulting in a lower power: inductance effect



### **Optical Interconnect: Modeling**

- Off-chip laser power source with 1.3µm wavelength
- On-chip quantum well modulators/Photodiode
- Trans-impedance receiver (TIR)
- Subsequent amplifier stage







### **Optical Interconnect: Power Dissipation**

#### Optical Modulator Power (QWM)

- Dynamic power: capacitance of modulator and the driving gates
- Static power: optical absorption in QWs

#### Receiver Power

- Criteria
  - ✓ Bit rate (BR)
  - ✓ Bit error rate (BER) = 10<sup>-15</sup>
  - Output voltage swing equal to the supply voltage

Optimize design parameters

Receiver power dramatically decreases with the detector capacitance: P. Kapur, IITC, 2002

✓ Device Capacitance:  $50 \text{fF} \rightarrow 10 \text{fF}$ 



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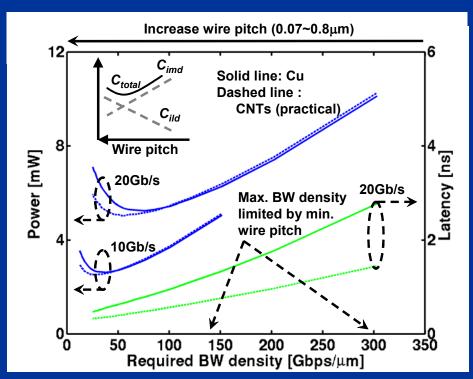
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# Performance Comparison: Power and Latency for Cu/low-K and CNT



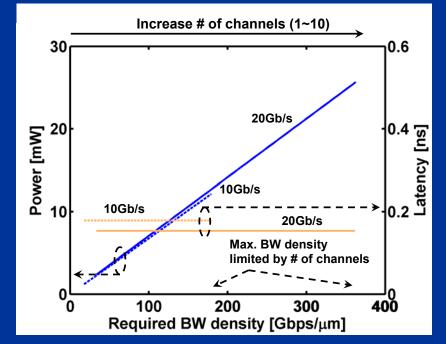
Wire length=10mm, 22nm technology node

- **BW density** limited by Min. pitch of ITRS: ~150Gbps/ $\mu$ m for  $f_{ck}$ =10Gbps
- Further limited by repeater area

**Power:** Wide wire pitch exhibits inductance effect

CNT have 1.5X lower latency compared to Cu/low-K

### Performance of Optics: Power and Latency

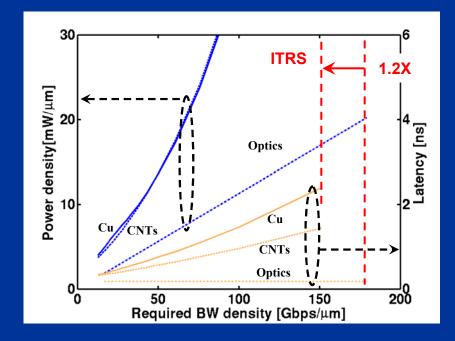


Wire length=10mm,  $C_{det}=C_{mod}=10$ , 22nm technology node

- □ Max. BW density limited by # of channels > Cu, CNTs @10 channels
- Power: linear with BW density
- Latency: constant



### Performance Comparison: Power density and Latency



Wire length=10mm, CNT: *mfp*=0.9µm, *PD*=1/3,  $C_{del}=C_{mod}$ =10fF,  $f_{ck}$ =10Gbps, 22nm technology node

Power density: Fundamentally low power for optics
 Latency: Optics ~4X faster than CNTs, CNTs ~1.5X faster than Cu
 BW Density: Optics~1.2X higher than CNTs and Cu



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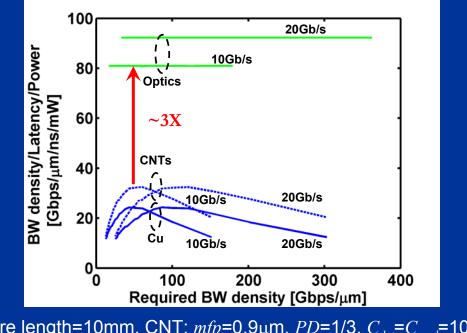
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### Performance Comparison: Compound metric

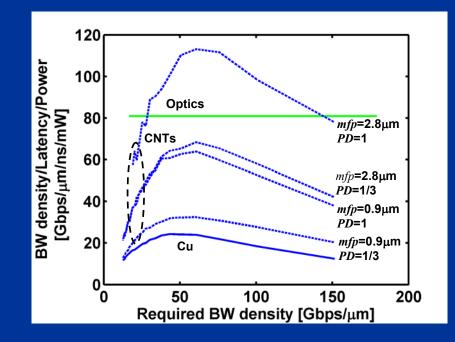


Wire length=10mm, CNT: *mfp*=0.9 $\mu$ m, *PD*=1/3, *C*<sub>det</sub>=*C*<sub>mod</sub>=10fF,  $f_{ck}$ =10Gbps, 22nm technology node

Optics ~3X higher CNTs @Maximum
 CNT, Cu: optimum wire pitch, maximizing metric: 3~5×W<sub>min</sub>



### Impact of CNT Parameters on Compound Metric



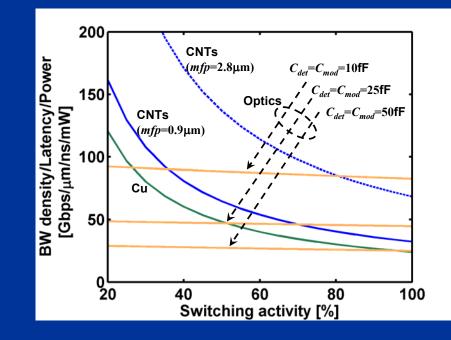
Wire length=10mm, CNT: *mfp*=0.9 $\mu$ m, *PD*=1/3, *C*<sub>det</sub>=*C*<sub>mod</sub>=10fF,  $f_{ck}$ =10Gbps, 22nm technology node

**CNTs:** ~1.4X better performance for Improving both *mfp* and *PD* 

□ Optics: device capacitances <10fF → enable optics have better performance</p>



### Impact of Switching Activity on Compound Metric



Wire length=10mm, CNT: *mfp*=0.9µm, *PD*=1/3,  $C_{del}=C_{mod}$ =10fF,  $f_{ck}$ =10Gbps, 22nm technology node

#### **Cu, CNTs: dynamic power** $\propto SA$ whereas Optics: static power $\sim SA$

- > Optics (10fF) vs. CNTs (*mfp*=0.9 $\mu$ m): cross-over *SA* ~ 40%
- > Optics (10fF) vs. CNTs ( $mfp=2.8\mu$ m): cross-over  $SA \sim 80\%$

#### **Optics is favorable for high SA**



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### Conclusion

Quantification of the circuit models (R, L, and C) of Cu and CNT

#### Comparison with primary metrics

- Power: CNTs (practical) ~ Cu < Optics</p>
- Latency: Optics < CNTs (practical) < Cu</p>

Comparison with compound metric: BW density/latency/power

Optics > CNTs (practical) > Cu

Evaluation of the impact of device/material/system parameters

- > System: global clock frequency ( $f_{ck}$ ), SA
- Material (CNT): *mfp* and *PD*
- Device Capacitance for Optics

Comparison framework gives the insight to system/device engineers which interconnect technology is proper to their system application

